

## Feature :

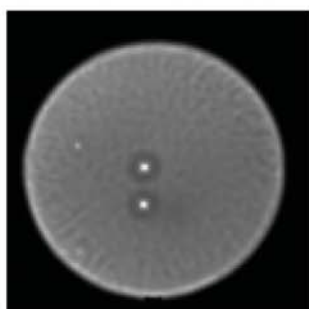
- ④ Detection Sensitivity better than 0.05 Micron Depth
- ④ Full View and 4X Zoom
- ④ 150-300 mm Wafer Sizes
- ④ Adjustable Sensitivity
- ④ Adjustable Intensity
- ④ Manual Loading
- ④ Rotating Wafer Chuck
- ④ Broad Beam Illumination with Narrow Band-Pass Filtered White Lamp
- ④ Defect Detection and Image Enhancement Software



The Magic Mirror™ is useful for detecting problems with many types of wafer processes:

- ④ Polishing
- ④ Epitaxy
- ④ Oxidation, Diffusion, CVD
- ④ Post Implant Annealing, RTP
- ④ CMP
- ④ SOI

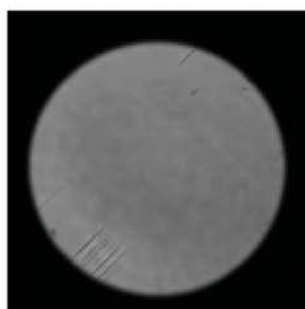
## Wafer Defects



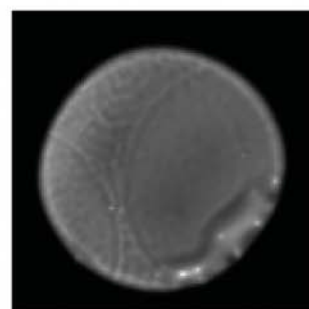
Dimples



SOI



Slip



Polishing Defects